

Fig.1 Schematic cross-sectional view of sapphire-based capacitive pressure sensor

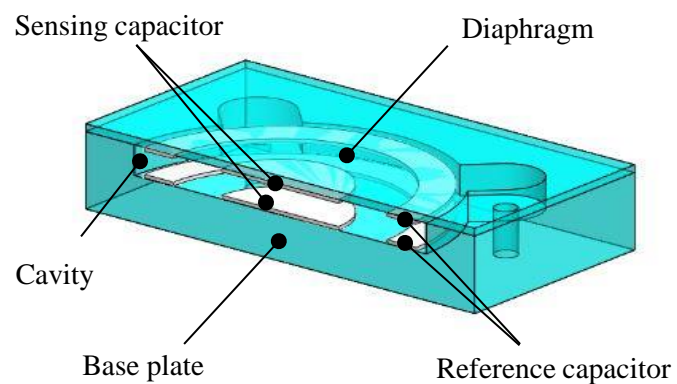


Fig.2 Schematic cross-sectional view of sensor chip

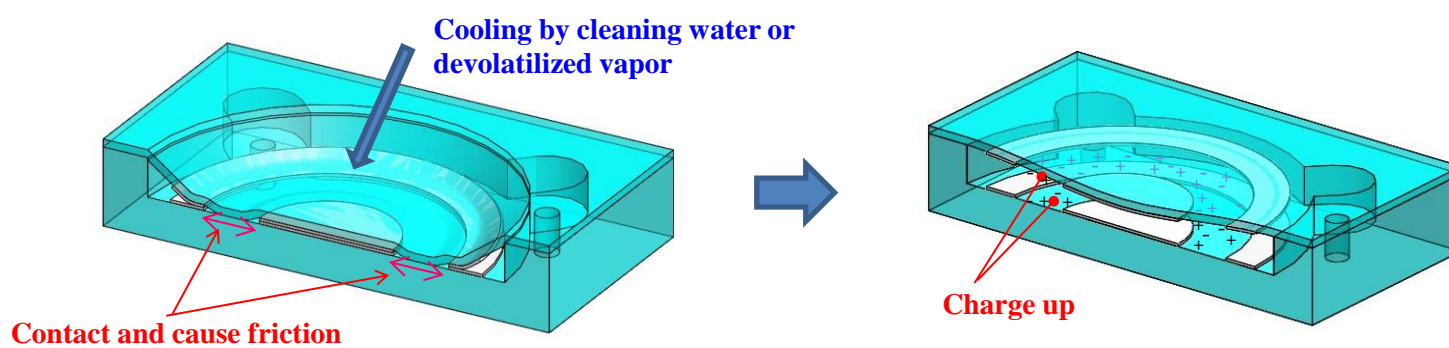


Fig.3 Schematic cross-sectional view of charging up on contacted surfaces of diaphragm and base-plate

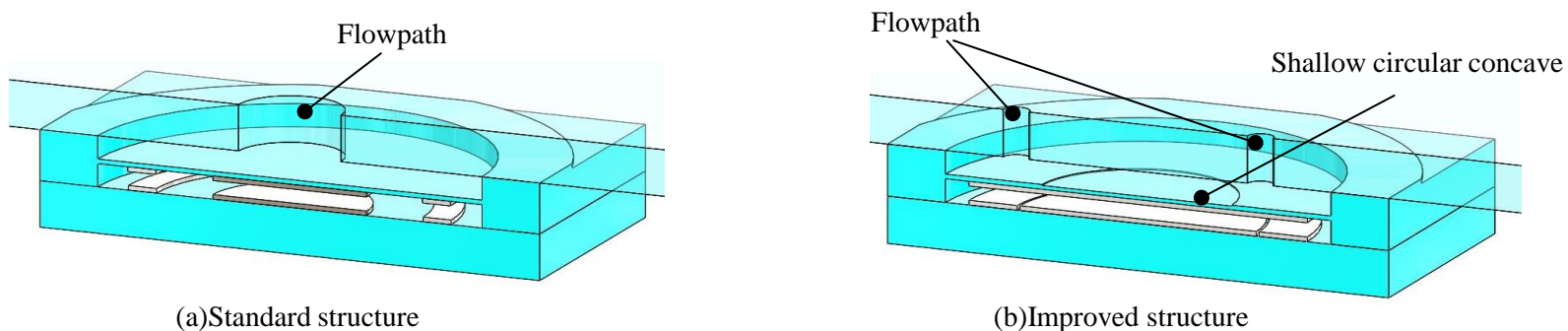
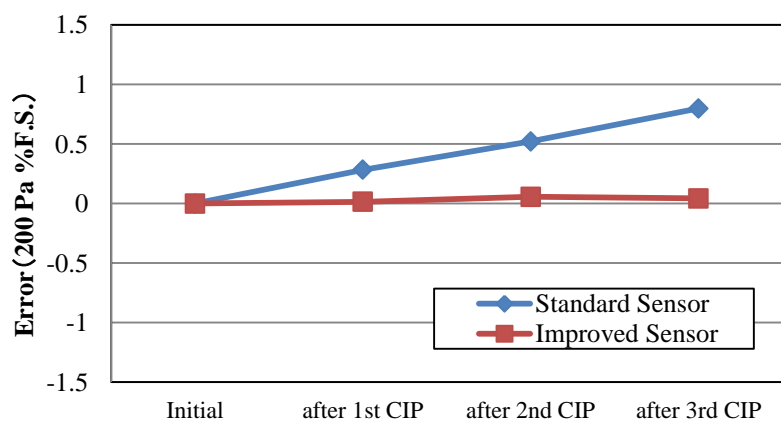
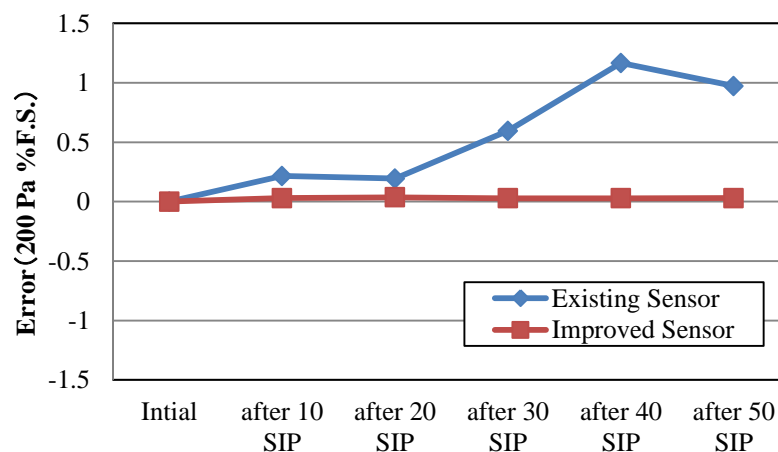


Fig.4 Schematic cross-sectional view of sensor chip and package structure



(a) Zero point shift before or after each CIP test (spray time: 1h, water temperature: R.T.)



(b) Zero point shift before or after each SIP test (1h, temperature: 123C)

Fig.5 Zero point shifts of CIP and SIP processes with improved sensor structure